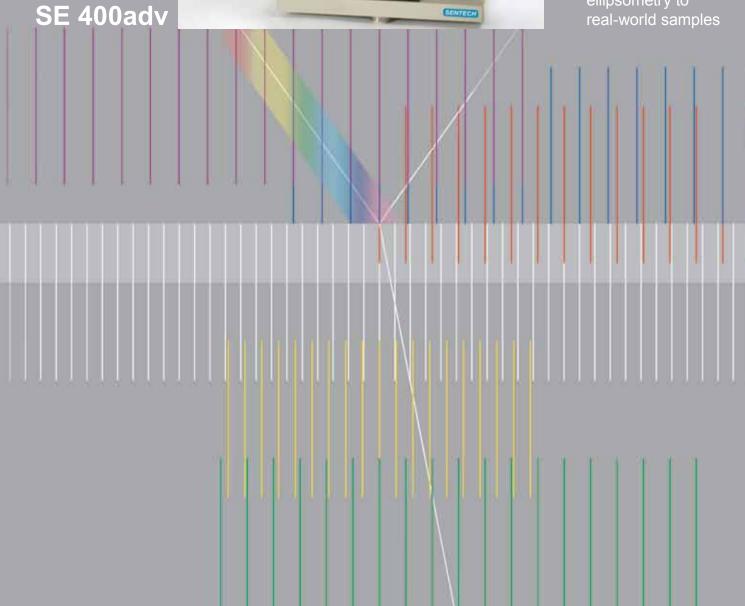


# Laser Ellipsometer

- Sub-Angstrom accuracy
- High speed
- It has never been easier to apply ellipsometry to real-world samples





Erfolg durch Leistung



Laser ellipsometer SE 400adv with controller

#### **Product description**

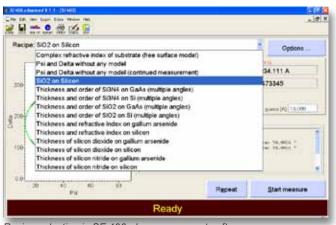
The SE 400adv can be utilized to characterize single films and substrates from selectable, application specific angles of

The auto-collimating telescope ensures precise measurement on most kinds of absorbing or transparent substrate with a flat, reflective surface.

The fully integrated support of multiple angle measurements (40°-90° in steps of 5°) can be used for determining thickness, refrative index, and extinction coefficent of layer stacks. Multiple angle measurements are also applied for absolute thickness measurement to compensate the ambiguity of measured thickness in laser ellipsometry.

The SE 400adv is the SENTECH laser ellipsometer for measuring thickness of ultra thin single films. The compact table top instrument comprises the ellipsometer optics, goniometer, sample platform, auto-collimation telescope, HeNe laser source, and detection unit.

The options of the SE 400adv support applications in microelectronic, photovoltaic, data storage, display technology, life science, metal processing, and others.



Recipe selection in SE 400adv measurement software

## SE 400adv Laser Ellipsometer

- Extraordinary high stability and accuracy
- Highly precise sample alignment
- Fast and comfortable measurement
- Fully integrated support of multiple angle measurements

### **Specifications**

Precision of Ψ, Δ at 90°  $\delta(\Psi) = 0.002^{\circ}$ (transmission) position:  $\delta (\Delta) = 0.002^{\circ}$ 

 $\delta(\Psi) = \pm 0.01^{\circ}$ Long term stability:  $\delta (\Delta) = \pm 0.1^{\circ}$ 

Precision

0.1 Å for 100 nm SiO<sub>2</sub> on Si of film thickness:

Precision

of refractive index:  $5 \times 10^{-4}$  for  $100 \text{ nm SiO}_2$  on Si

PCSA with compensator Setup:

1 mm Diameter of laser spot:

Angle of incidence: manual goniometer

40°-90°, set in steps of 5°

auto collimating telescope (ACT) Sample alignment:

for manual sample tilt and height

adjustment

#### **Options**

- Microspots (25 µm)
- Mapping stages (50 mm to 300 mm)
- Liquid cells
- Video camera
- Autofocus
- Video camera
- Computer controlled goniometer
- Simulation software
- Certified reference wafers

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